

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant : Shunji MAEDA *et al.*  
Serial No. : Unassigned (§53(b) Cont. of 10/098,478 filed 18 March 2002)  
Filed : 17 October 2003  
For : MANUFACTURING METHOD OF SEMICONDUCTOR  
SUBSTRATE AND METHOD AND APPARATUS FOR  
INSPECTING DEFECTS OF PATTERNS OF AN  
OBJECT TO BE INSPECTED  
Art Unit : Unassigned (Parent - 2877)  
Examiner : Unassigned (Parent - Hoa Q. Pham)  
Conf. No : Unassigned (Parent - 5054)

**PRELIMINARY AMENDMENT**

**Mail Stop Patent Application**

Commissioner for Patents

POB 1450

Alexandria, Virginia 22313-1450

17 October 2003

Sir:

Prior to calculating the filing fee for the above-identified application, the following amendments and remarks are respectfully submitted.

In accordance with the revised format of the manner of making amendments under 37 CFR §1.121 as set forth in the Final Rule effective 30 July 2003, each section of amendment herein begins on a new page, and changes are shown by strike-through (or double brackets where appropriate) and underlining to indicate deletions and additions, respectively. A complete listing of all claims ever presented in the application is given with the current status of each claim, and only the text of all pending and withdrawn claims is presented in full, with those not being amended herein being presented in clean version.